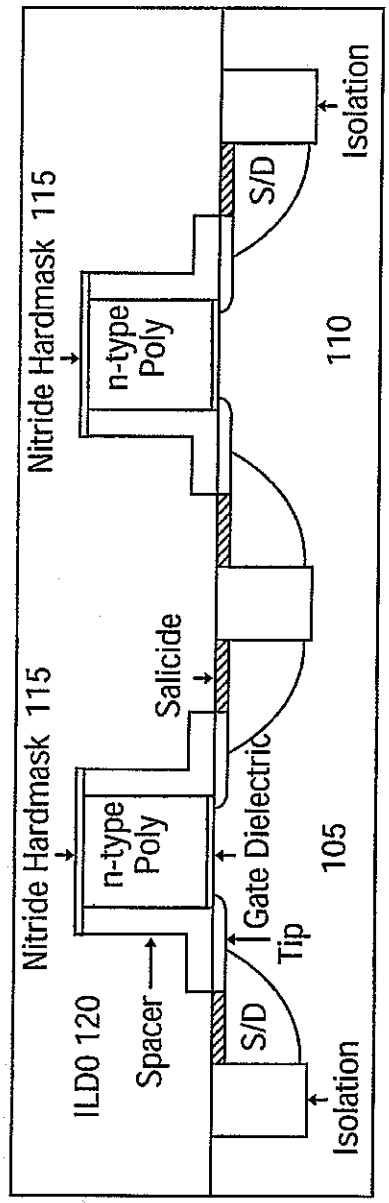

Nitride Hardmask 115
n-type Poly
S/D
Isolation
110
Nitride Hardmask 115
Salicide
ILD0 120
Spacer
S/D
Tip
Gate Dielectric
105
Isolation

FIG. 1

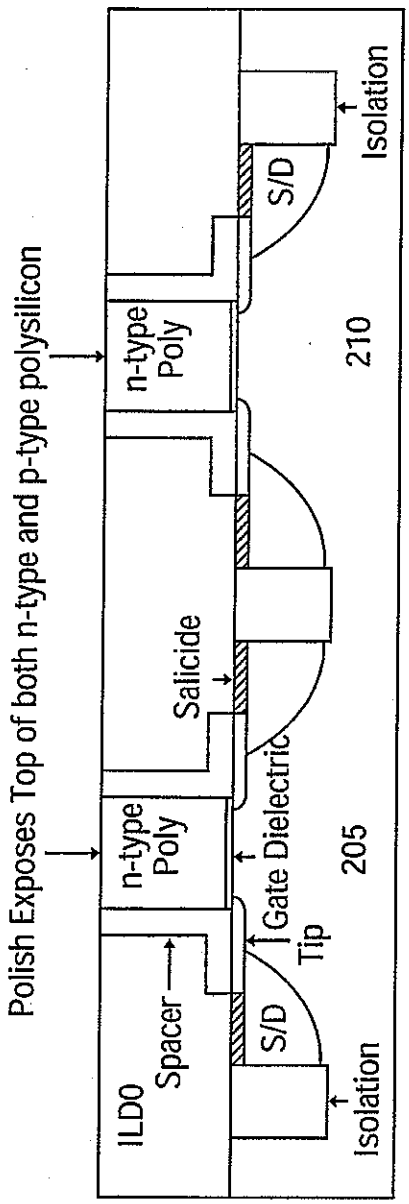

Polish Exposes Top of both n-type and p-type polysilicon
n-type Poly
S/D
Isolation
210
Salicide
ILD0
Spacer
S/D
Tip
Gate Dielectric
205
Isolation

FIG. 2

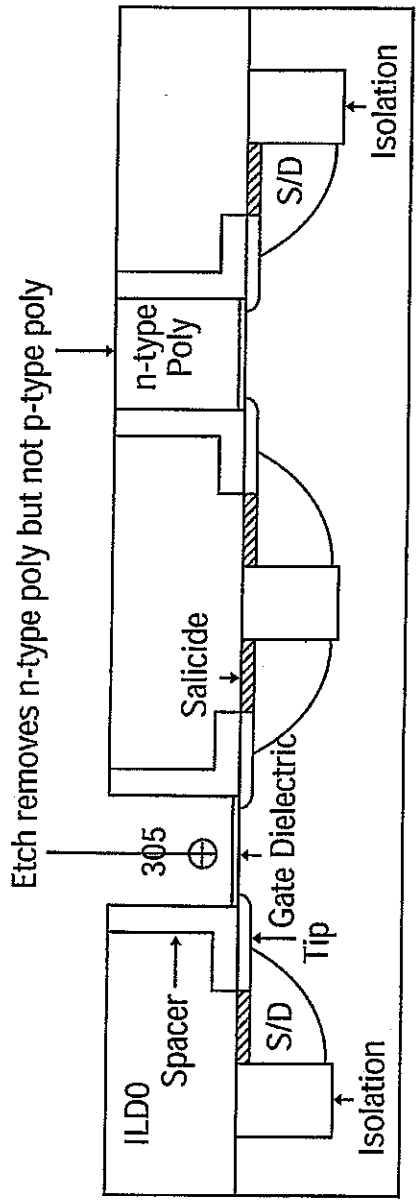

Etch removes n-type poly but not p-type poly
305
n-type Poly
Salicide
Gate Dielectric
Tip
Spacer
ILD0
S/D
S/D
Isolation
Isolation

FIG. 3

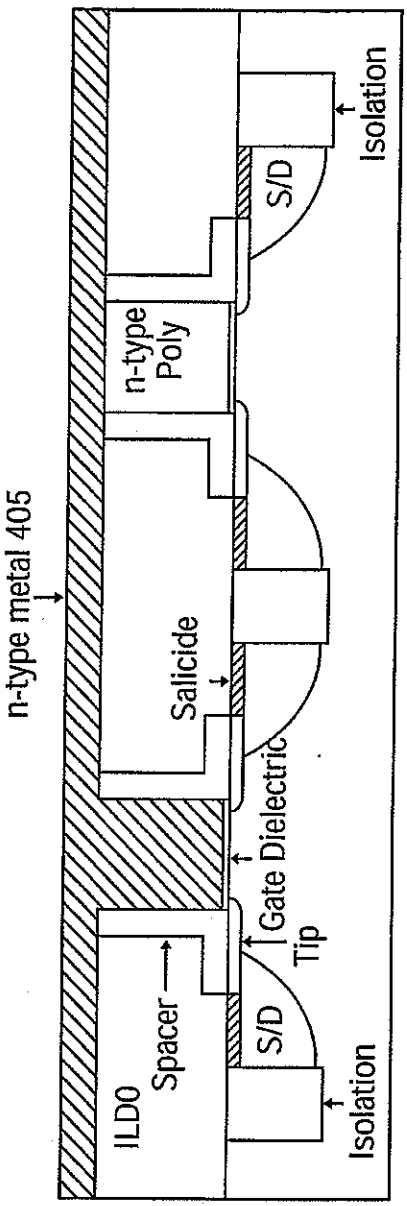

n-type metal 405
n-type Poly
Salicide
Gate Dielectric
Tip
Spacer
ILD0
S/D
S/D
Isolation
Isolation

FIG. 4

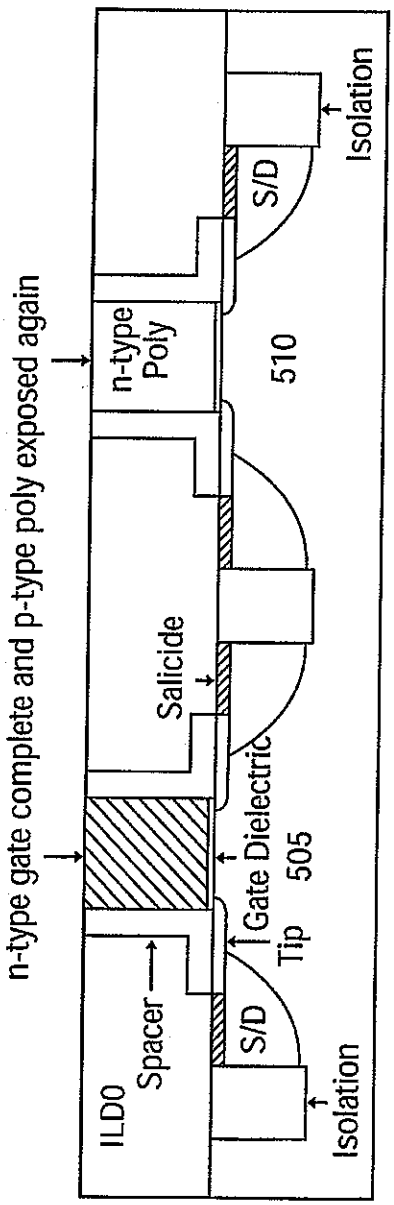

n-type gate complete and p-type poly exposed again
n-type Poly
510
S/D
Isolation
Salicide
Gate Dielectric
Tip
505
ILD0
Spacer
S/D
Isolation

FIG. 5

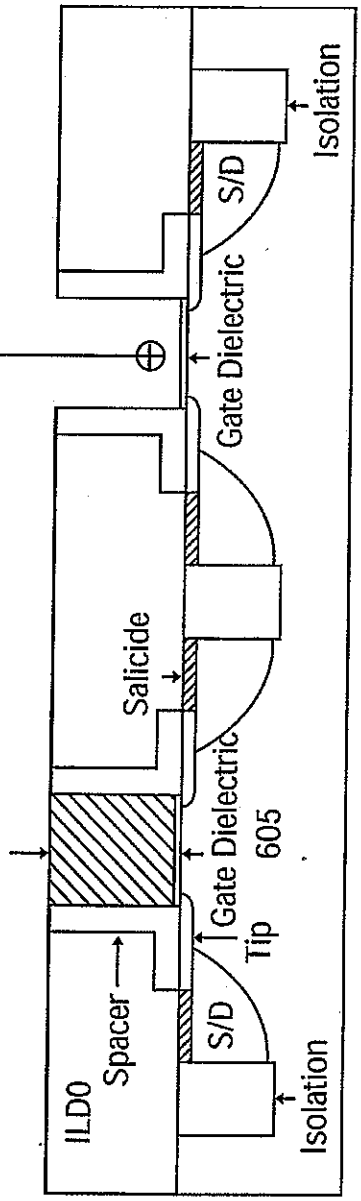

Etch removes p-type poly but not the n-type metal
S/D
Isolation
Gate Dielectric
Salicide
Gate Dielectric
Tip
605
ILD0
Spacer
S/D
Isolation

FIG. 6

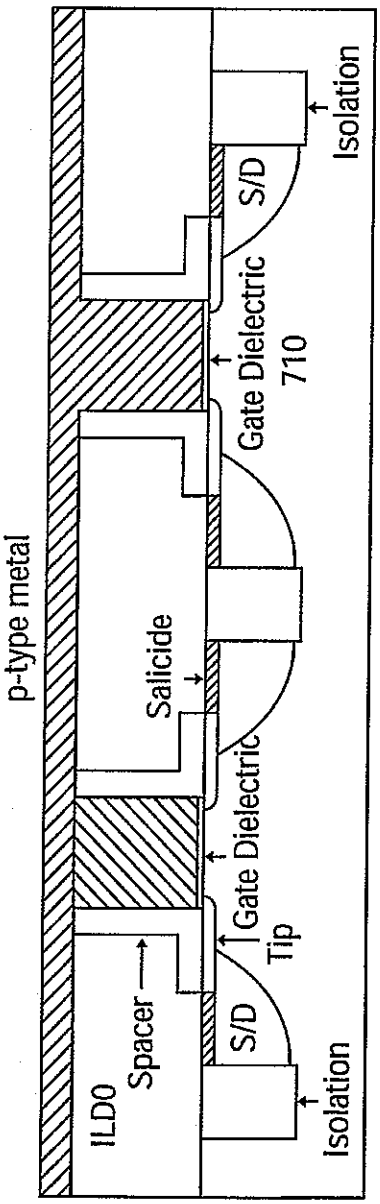

p-type metal
Salicide
Gate Dielectric
Tip
S/D
Isolation
Gate Dielectric
710
S/D
Isolation
ILD0
Spacer

FIG. 7

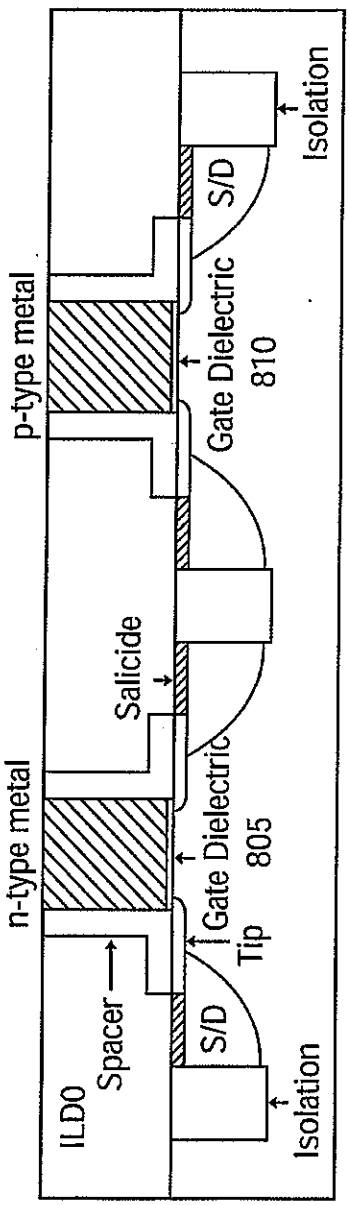

p-type metal
Salicide
Gate Dielectric
Tip
S/D
Isolation
Gate Dielectric
810
S/D
Isolation
n-type metal
805
ILD0
Spacer

FIG. 8

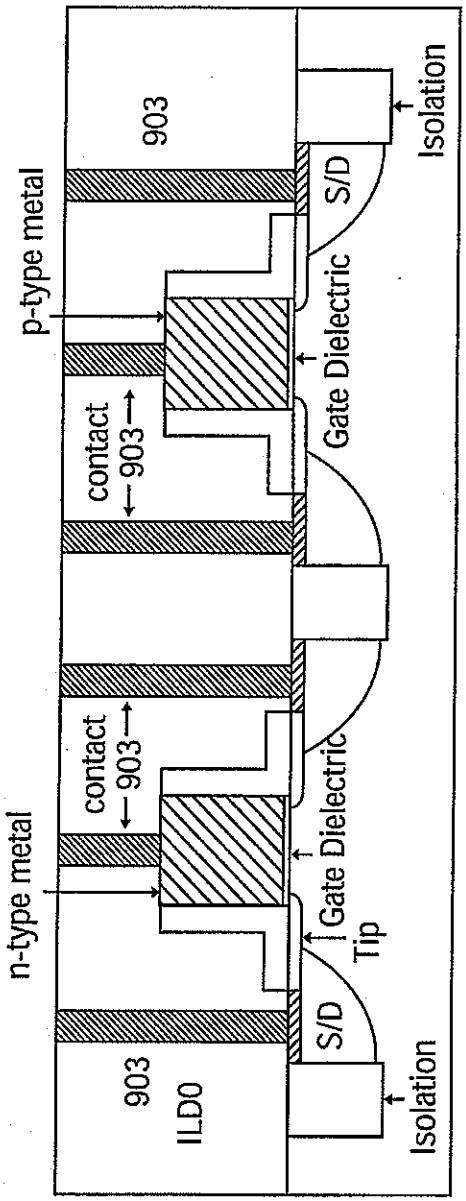

903
p-type metal
Isolation
S/D
Gate Dielectric
contact
903
contact
903
n-type metal
Gate Dielectric
Tip
S/D
903
ILD0
Isolation

FIG. 9

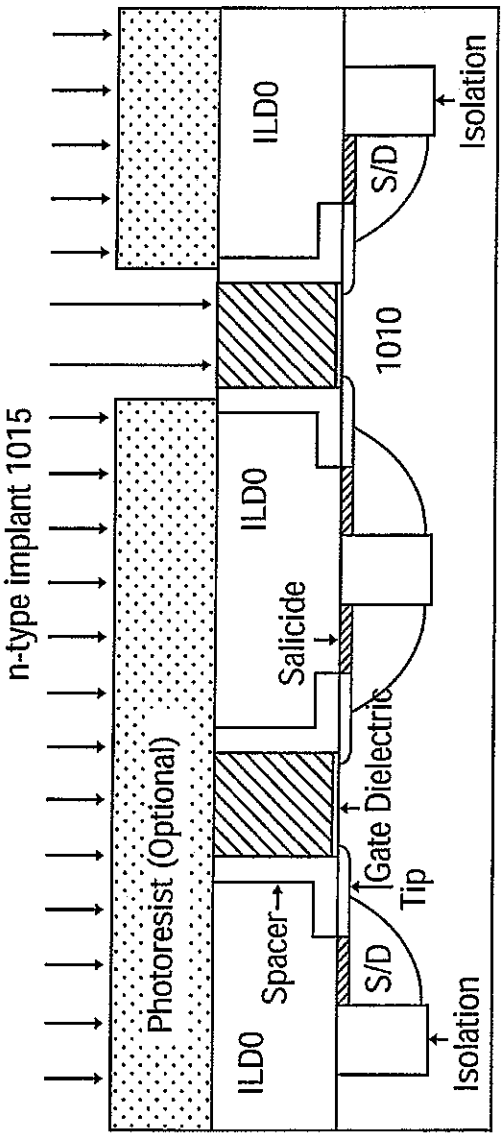

n-type implant 1015
Photoresist (Optional)
ILD0
Isolation
S/D
1010
ILD0
Salicide
Gate Dielectric
Spacer
Tip
S/D
ILD0
Isolation

FIG. 10

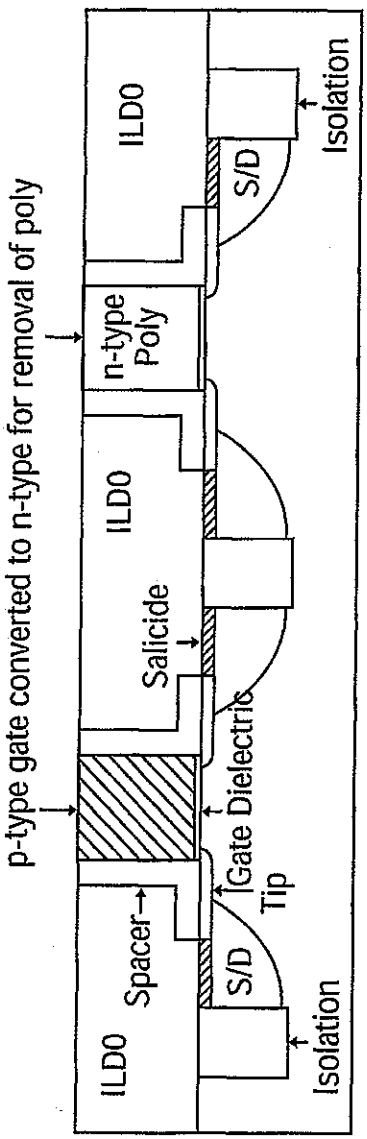

p-type gate converted to n-type for removal of poly
ILD0
n-type Poly
ILD0
Salicide
Gate Dielectric
Tip
Spacer
S/D
S/D
Isolation
Isolation
ILD0

FIG. 11

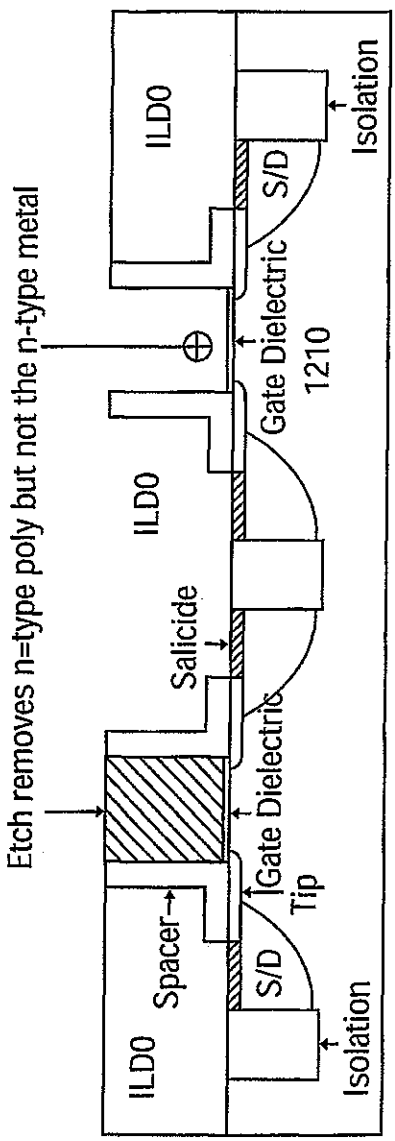

Etch removes n=type poly but not the n-type metal
ILD0
Gate Dielectric
1210
ILD0
Salicide
Gate Dielectric
Tip
Spacer
S/D
S/D
Isolation
Isolation
ILD0

FIG. 12